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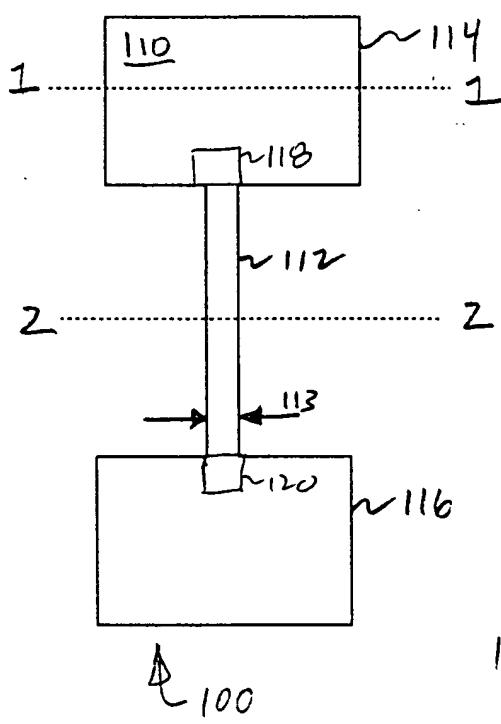


FIG. 1A

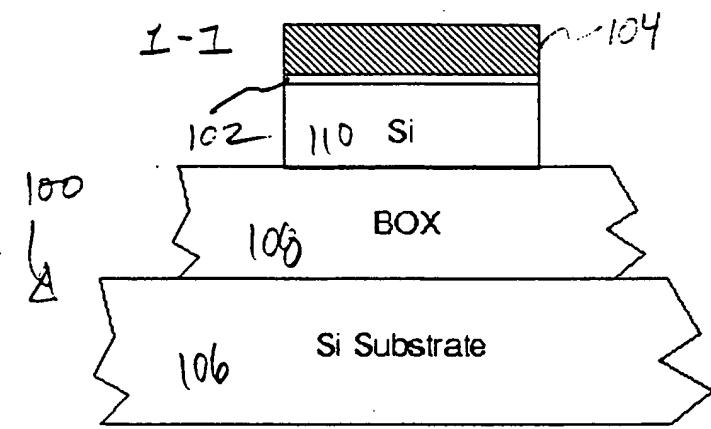


FIG. 1B

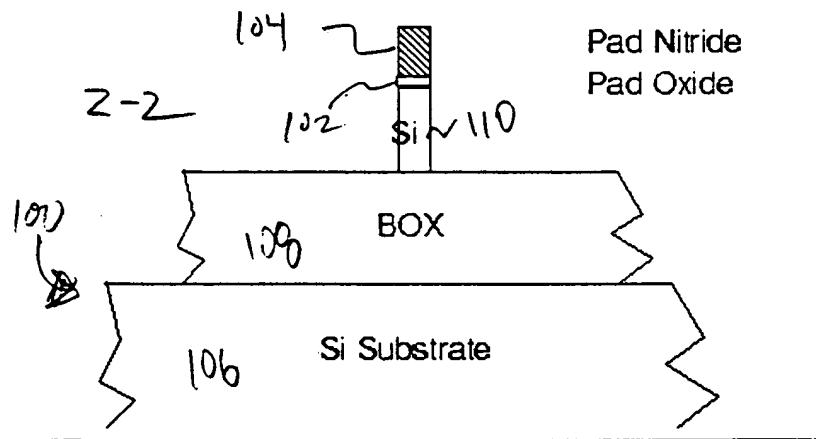


FIG. 1C

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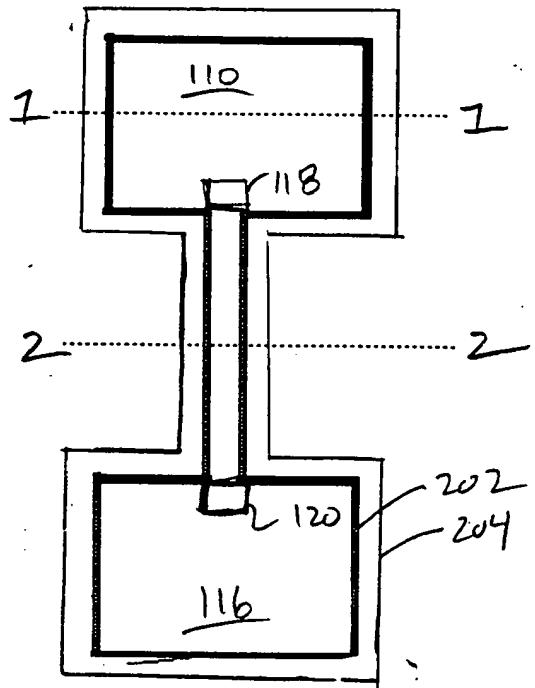


FIG 2A

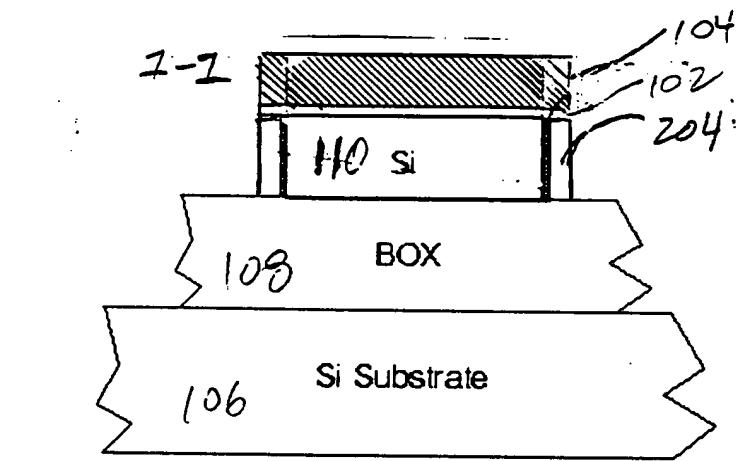


FIG 2B

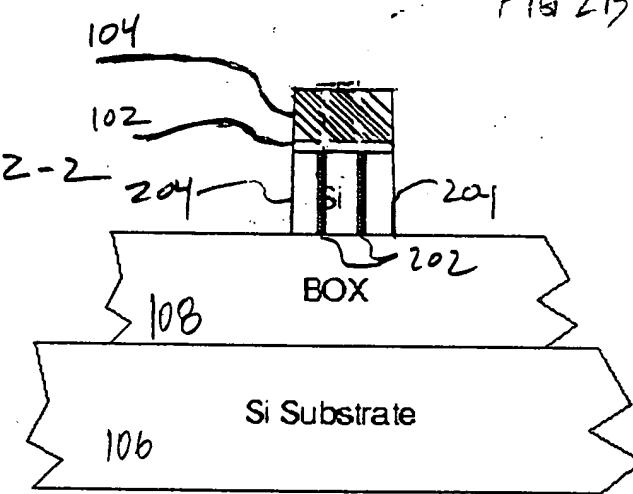


FIG 2C

FIG. 2

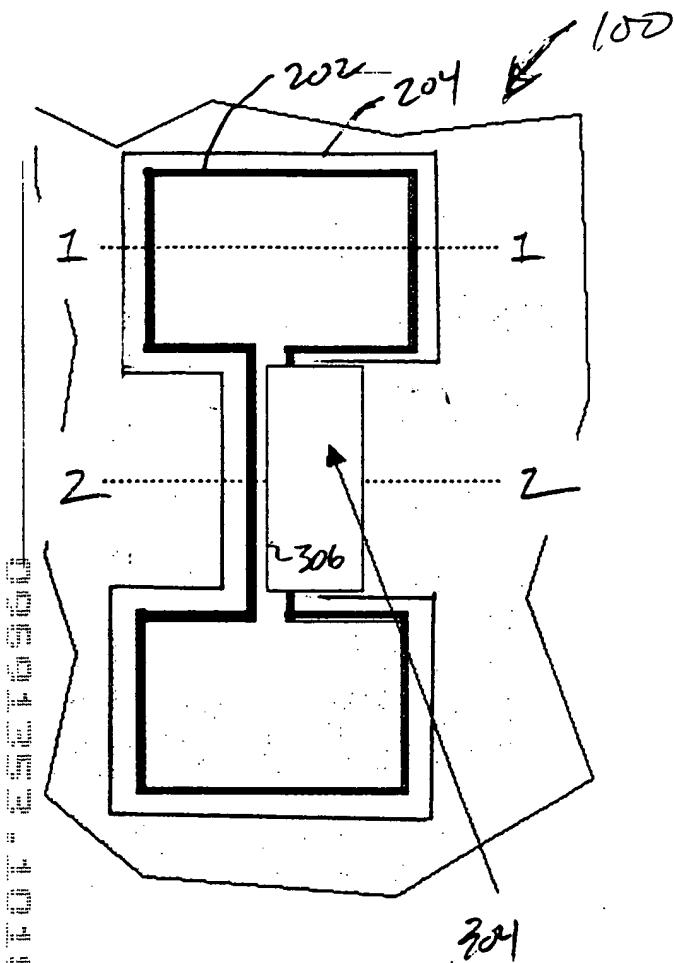


FIG 3A

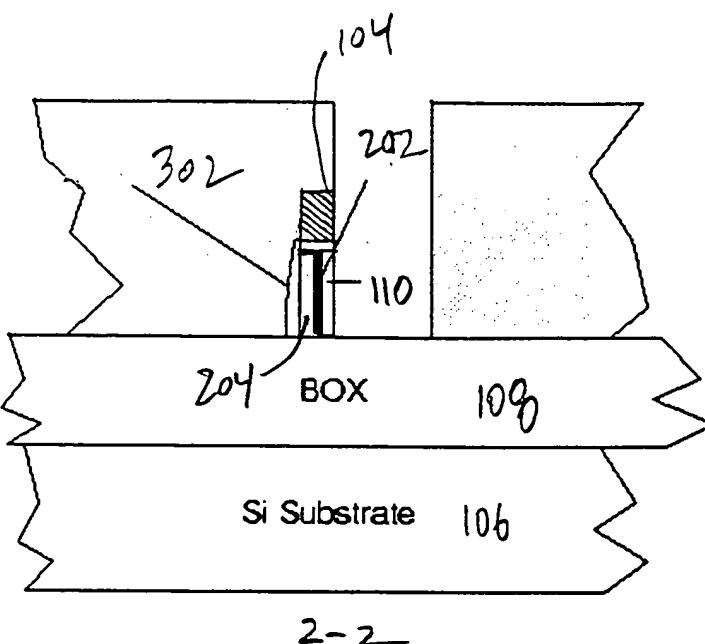
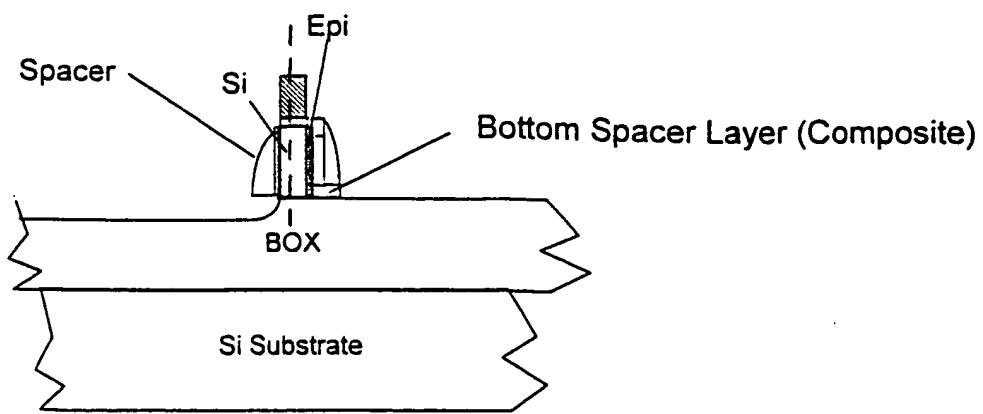


FIG 3B

Fig. 3



B-B CX

FIG. 12

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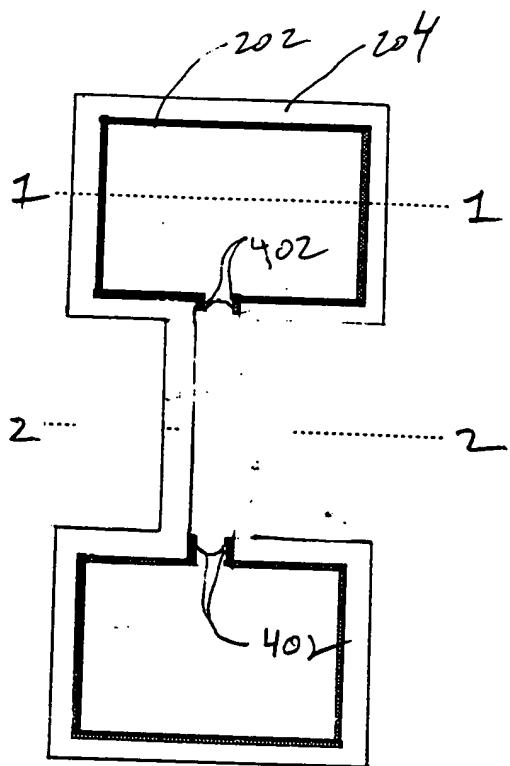


FIG. 4A

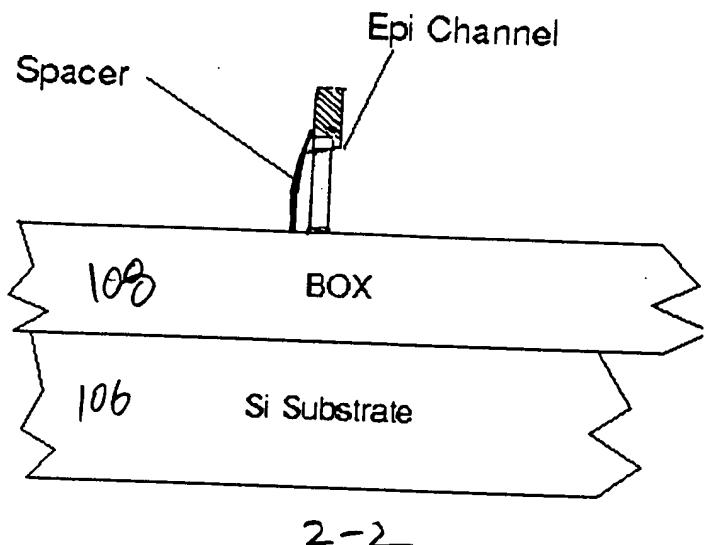


FIG. 4B

FIG. 4

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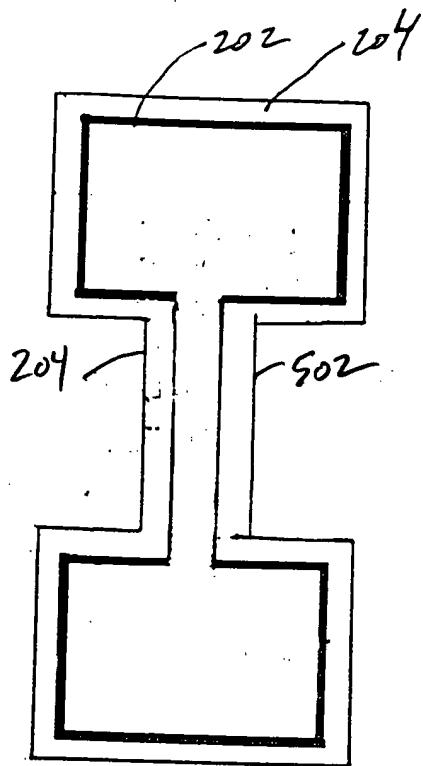


FIG 5

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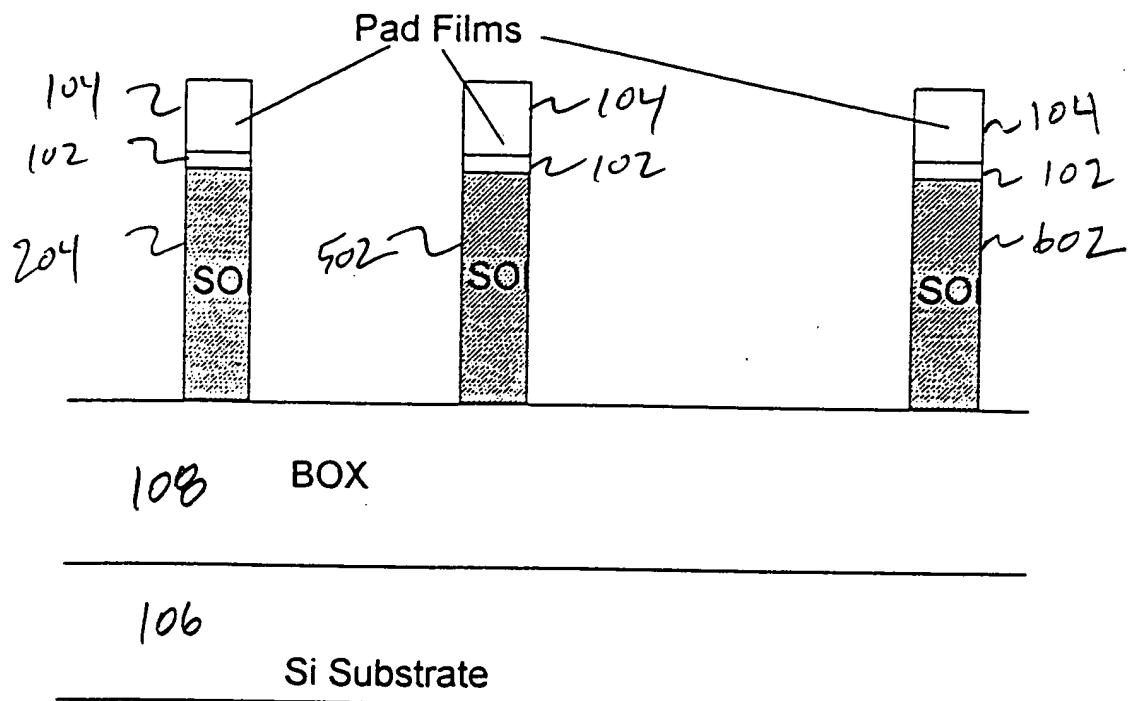


Fig 6

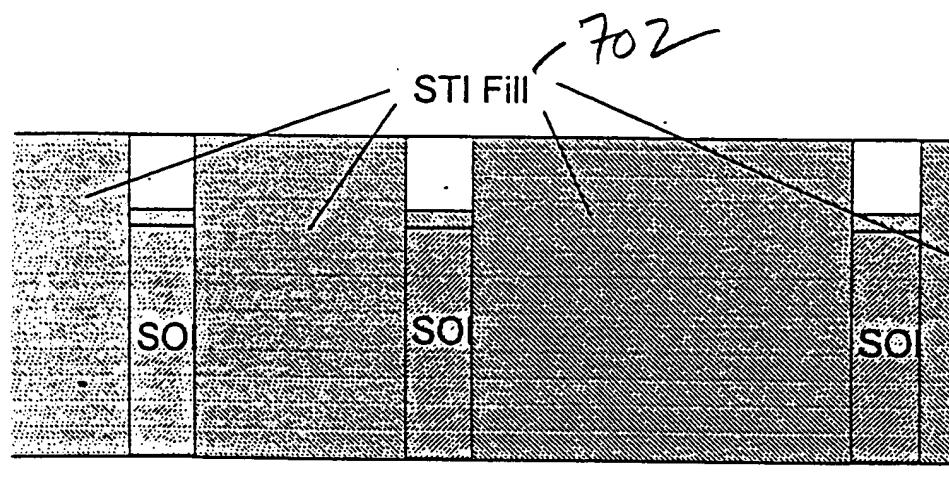


Fig 7

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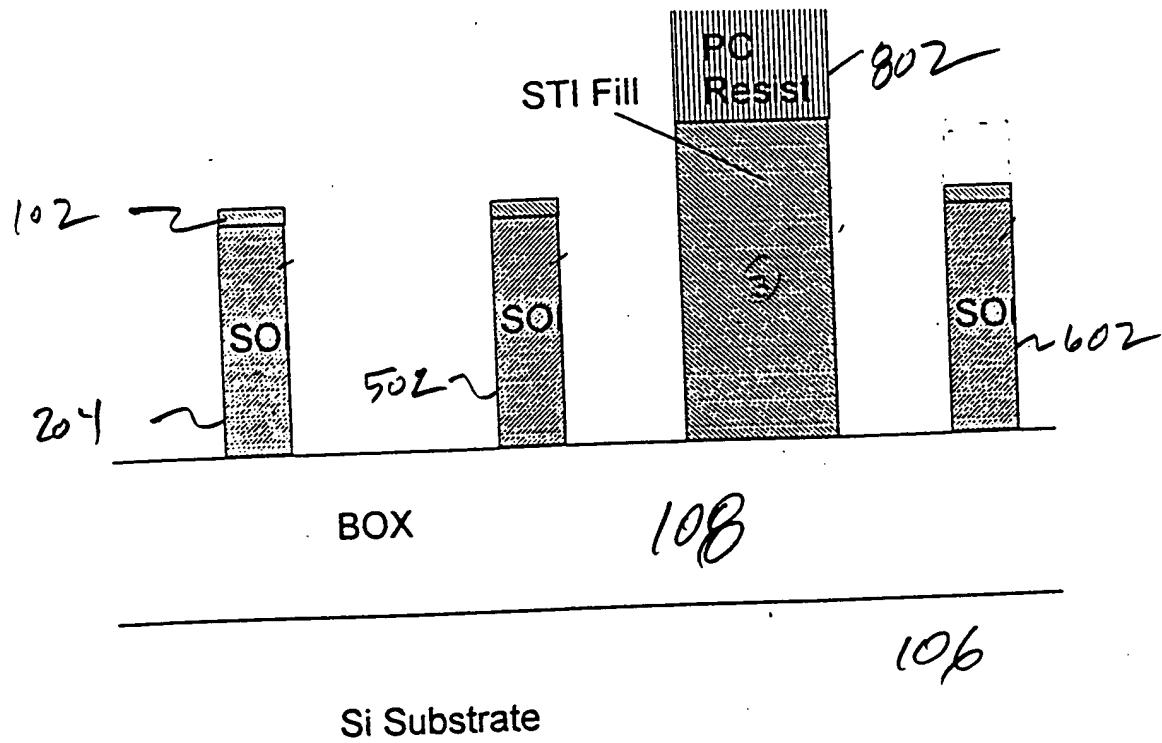


Fig 8A

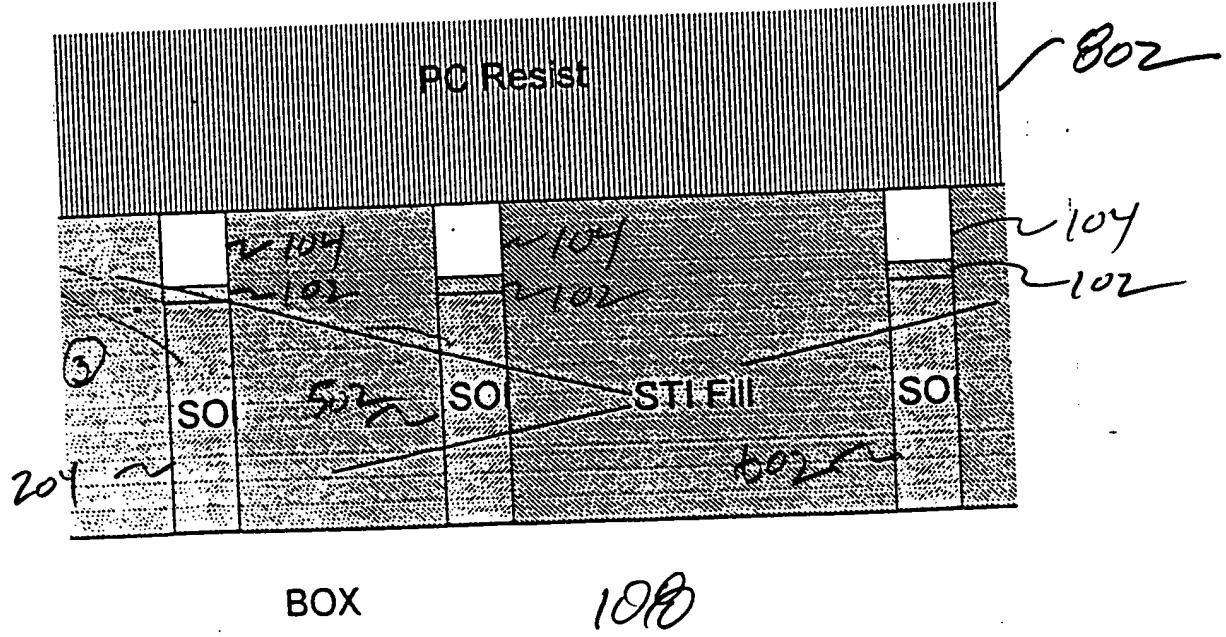
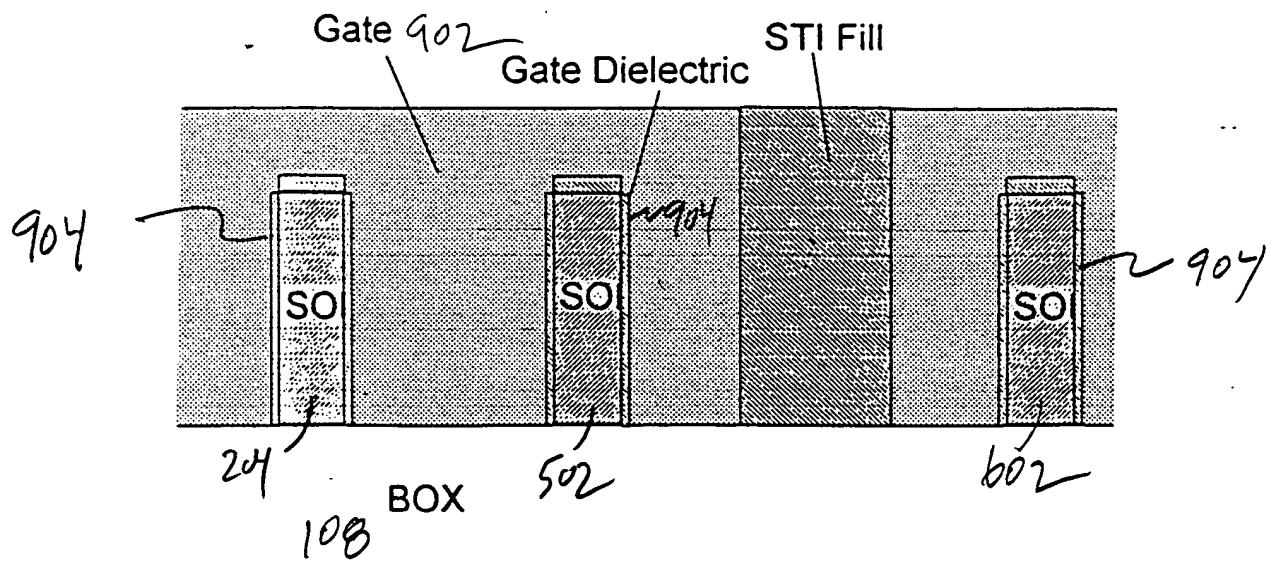


Fig 8B

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Si Substrate

Fig 9A

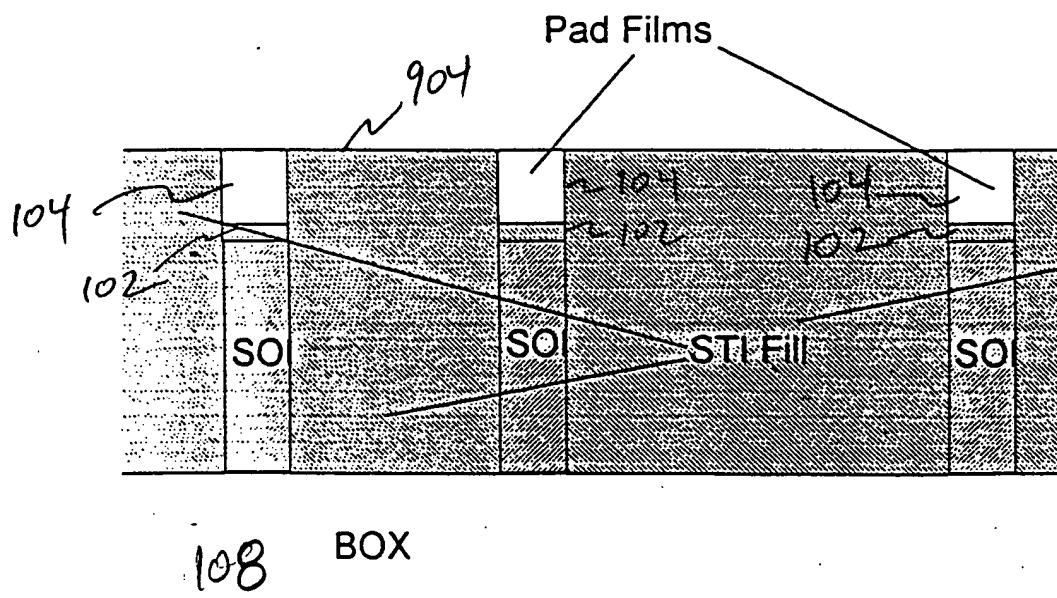


Fig 9B

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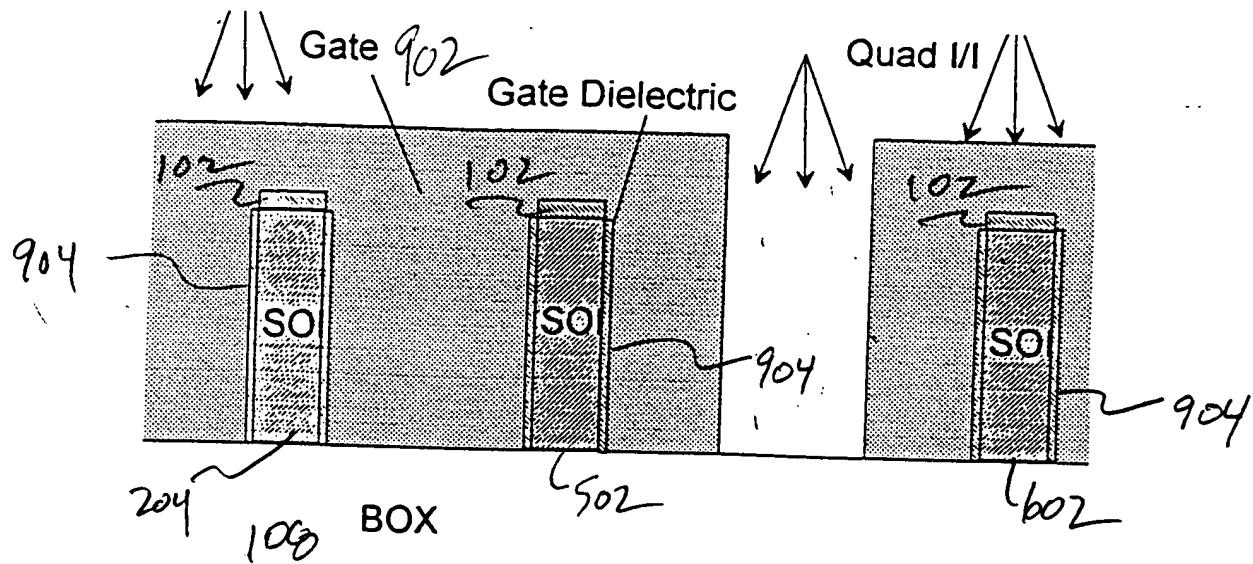


Fig 10A

Extension Implant - Done w/ angle relative to substrate and repeated 4 times at cardinal directions relative to notch.

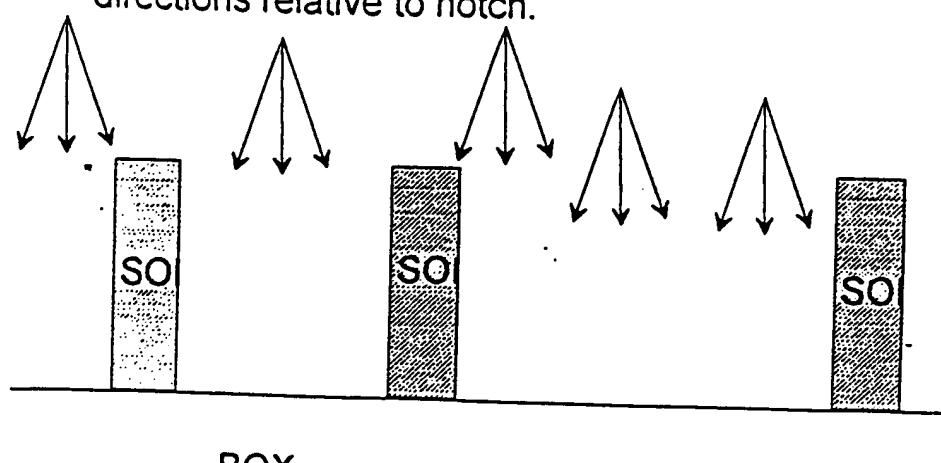


Fig 10B

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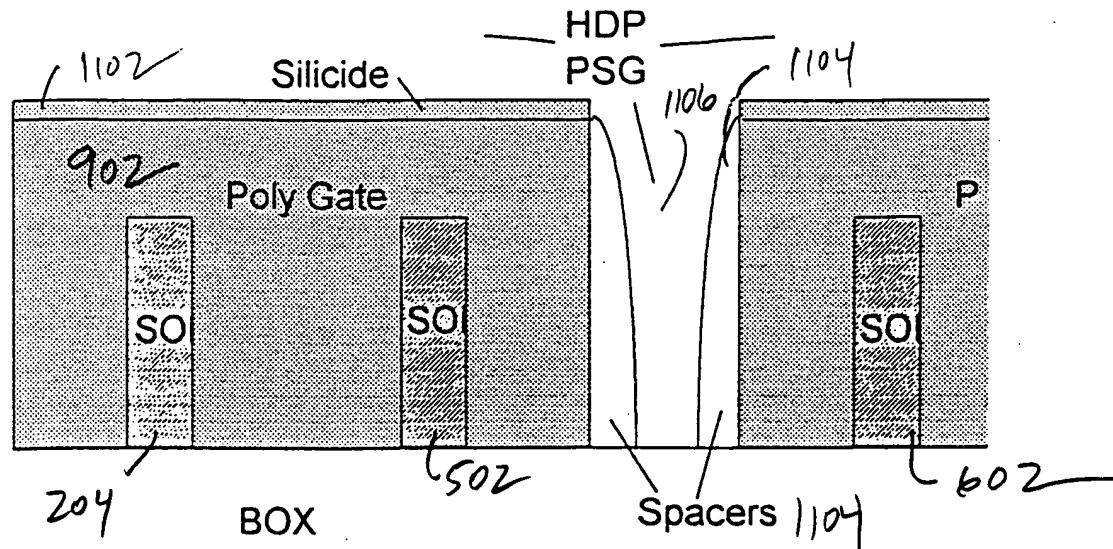


Fig 11A

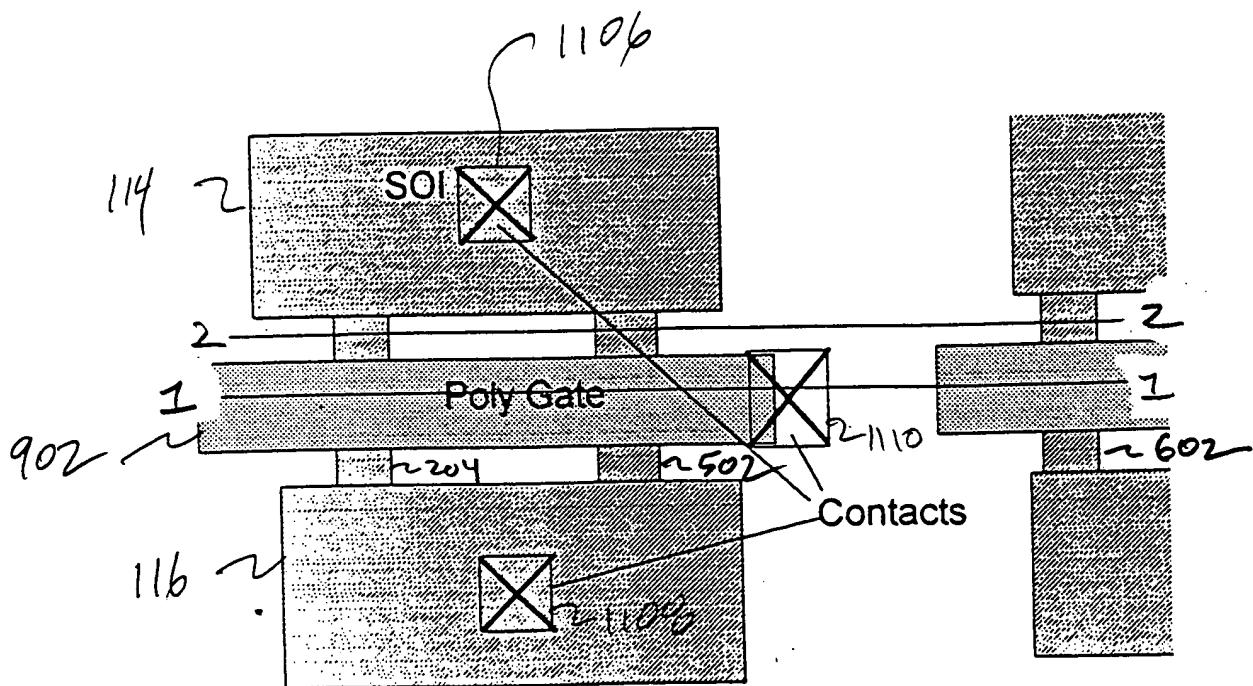


Fig 11B